PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Kiermasz et al.

Application No: 10/607,613

Filed: June 27, 2003

For: PLATEN WITH DIAPHRAGM AND METHOD

PATENT

Docket No: LAM2P421

| Examiner: Rachuba, M. T. |
| Group Art Unit: 3723

FOR OPTIMIZING WAFER POLISHING

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Alexandria, VA 22313-1450, on August 29, 2005.

Signed:

REQUEST FOR CONTINUED EXAMINATION (RCE) TRANSMITTAL

Mail Stop: RCE, Commissioner for Patents, Alexandria, VA 22313-1450

Sir:

This is a Request for Continued Examination (RCE) under 37 CFR 1.114 of the above-identified application.

1.	Subm	nission required under 37 C.F.R. § 1.114
	a.	Previously submitted
		i. Consider the amendment(s)/reply under 37 C.F.R. § 1.116 previously
		filed on
,		ii. Consider the arguments in the Appeal Brief or Reply Brief previously
		filed on
		iii. Other
	b.	□ Enclosed
		i. Amendment/Reply
		ii. Affidavit(s)/Declaration(s)
		iii. Information Disclosure Statement (IDS)
		iv.
2.	Misce	ellaneous
	a.	Suspension of action on the above-identified application is requested under 37
		C.F.R. § 1.103(c) for a period of months.
	b.	Other
3.	Fees	
	a.	$\boxtimes$ Check in the amount of \$790.00 is enclosed for:
		i. RCE fee required under 37 C.F.R. § 1.17(e);
		ii. Extension of time fee (37 C.F.R. §§ 1.136 and 1.17); and
		iii. Other
	b.	☐ The Director is hereby authorized to charge any fees, or credit any
		overpayments, to Deposit Account No. 50-0805 (Order No. <u>LAM2P421</u> ).
Da	te: A	ugust 29, 2005 hute
		Chester E. Martine, Jr.
		Registration No. 19,71/1

Customer No. 25920